

## IN THE CLAIMS:

Please amend the claims, as follows:

Claim 1. (currently amended) A device for the inspection of surfaces (10) ~~notably for the inspection of the surface (surfaces) (10)~~ of one or more semiconductors (14), which ~~device includes~~, comprising:

at least one laser light source (1); and

a detector (28) for light (13) that is reflected by the surface (10) to be inspected;

and

~~characterized in that the device includes~~ at least one mode filter (15; 15.1) ~~that is associated with the reflected light (13) between the surface (10) and the detector (28).~~

2. A device ~~as claimed in~~ according to claim 1, ~~characterized in that wherein~~ the mode filter (15; 15.1) suppresses ~~that a~~ mode in the reflected light (13) that corresponds to ~~the a~~ mode of the laser light source (1).

3. A device ~~as claimed in~~ according to claim 1, ~~characterized in that the device includes wherein the mode filter comprises~~ a beam splitter (21) which splits a light beam (13) into at least two sub-beams (13.2; 13.3) that interfere with one another.

4. A device ~~as claimed in~~ according to claim 3, ~~characterized in that wherein the mode filter includes a device (22) for mode-selective phase shifting and~~ one of the sub-beams (13.3) traverses ~~the a~~ device (22) for mode-selective phase shifting.

5. A device ~~as claimed in~~ according to claim 4, ~~characterized in that wherein~~ the

device (22) ~~effects~~ realizes a phase shift of a mode through  $180^\circ$  overall, together with the a difference in path length, so that the sub-beams (13.2; 13.3) interfere destructively in respect of this mode.

6. A device ~~as claimed in~~ according to claim 5, ~~characterized in that~~ wherein the device (22) includes a lens system (26; 27) that operates on the a basis of the Guoy phase system basis ~~is provided~~ so as to ~~realize~~ effect the phase shift through  $180^\circ$ .

9. A method for the inspection of ~~surfaces, notably for the inspection of the surface (surfaces)~~ a surface of one or more semiconductors, comprising the steps of:  
said surface being irradiated irradiating said surface by means of at least one laser light source; and  
detecting the light that is reflected by the surface to be inspected ~~being detected~~ in at least one detector, ~~characterized in that~~ wherein the laser light source emits light of a defined mode and that light that is reflected by the surface is guided through a mode filter.

10. A method ~~as claimed in~~ according to claim 9, ~~characterized in that~~ wherein the mode filter suppresses the mode of the laser light source and ~~that~~ no signal is detected ~~in the case of where reflection that~~ does not affect the mode.